

**Interferometrische Messeinrichtung zum Erfassen der Form oder des Abstandes insbesondere rauher Oberflächen****Publication number:** JP2002505414T**Publication date:** 2002-02-19**Inventor:****Applicant:****Classification:****- International:** G01B9/02; G01B11/14; G01B11/30; G01J9/04;  
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7): G01B9/02; G01B11/14; G01B11/30**- European:** G01B11/30B; G01J9/04**Application number:** JP20000533712T 19990216**Priority number(s):** DE19981008273 19980227; WO1999DE00433  
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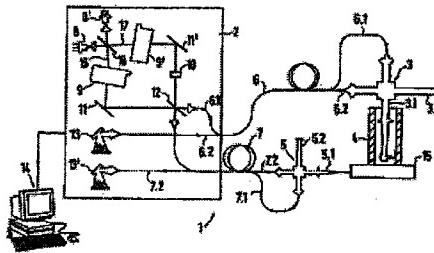
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Abstract not available for JP2002505414T

Abstract of corresponding document: **DE199808273**

The invention relates to an interferometric measuring device (1) for determining the profile of rough surfaces. A spatially coherent beam generating unit is provided. Said unit emits temporally briefly coherent wideband radiation. The device is divided into a section with the components of a modulation interferometer (2) and a section with the components of a measuring probe (3). The measuring probe (3) is linked to the modulation interferometer (2) by an optical fibre system (6) and can be used at a distance from the modulation interferometer (2).

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